Overview of Device SEE Susceptibility from Heavy Ions

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J. W. Cole, Maj. USAF

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OVERVIEW OF DEVICE SEE SUSCEPTIBILITY FROM HEAVY IONS

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Abstract

A fifth set of heavy ion single event effects (SEE) test data have been collected since the last IEEE publications (1, 2, 3, 4) in December issues for 1985, 1987, 1989 and 1991. Trends in SEE susceptibility (including soft errors and latchup) for state-of-the-art parts are evaluated.

Introduction

Ongoing SEE test programs at JPL ,The Aerospace Corporation, the European Space Agency (ESA), CNES and other organizations are continuing to assess specific part performance for interplanetary and satellite environments and to establish SEE response trends of an ever-increasing body of device data.

In 1985, Nichols et al (Ref. 1) published the first nearly comprehensive listing of SEE test data for 186 parts. This presentation was updated in 1987 (Ref. 2) with the publication of data for 83 additional parts, in 1989 (Ref. 3) with data for 154 parts, and in 1991 (Ref. 4) with data for 182 parts. In this paper, the authors extend the data base for 165 new parts. As before, the data are collected according to technology, function and manufacturer in order to identify trends, generalizations and data gaps.

Testing Approaches

The experimental procedures, such as those used by JPL and The Aerospace Corporation, are evolutionary and are described in detail from time to time in December issues of IEEE Transactions on Nuclear Science (5,6) or in in-house reports. In general, procedures comply with the guidelines for SEE testing set forth by the ASTM F1.11 document (7). They also comply with a JEDEC 13.4 document in preparation, "Test Procedure for the Measurement of Single Event Effects in Semiconductor Devices from Heavy Ion Irradiation."

Organization and Scope of Data

This paper summarizes soft error and latchup experimental test data from the Jet Propulsion Laboratory (JPL), The Aerospace Corporation (A), John Hopkins Applied Physics Laboratory (JH), Centre National D'Etudes Spatiales (CNES, France), European Space Agency (ESA) and other SEE testers. These data are provided directly to JPL or were otherwise made available to the community during the two-year period from January, 1991, through December, 1992. We are pleased to include smaller SEE data sets generated by all U. S. and foreign researchers when these data are made directly available to us. Not included are proprietary data generated by subcontractors who used JPL hardware. Also omitted are now fairly extensive data sets on power transistor burnout obtained by JPL, Rockwell, Boeing and others—such data require a significantly different organization.

The SEE data presented here and in the previous four reports (1,2,3, 4) represent a substantial majority of all test data obtained on SEE throughout the world. Some additional data may exist in other articles of this publication (IEEE-Nuclear Science [Dec. 1993] or this conference's IEEE Workshop Record), in other journals or in published and unpublished presentations of SEE symposia.

The data from all organizations are summarized and collected together even though there are differences in the data from each organization. For example, JPL defines the threshold LET as that value of LET where soft errors are first counted at fluences of 10⁶ ions/cm²; Aerospace now defines their LET threshold as occurring at that point where the measured upset cross section is 0.01 times the measured maximum cross section, CNES reports a threshold at 0.1 times the saturated cross section. JPL's definition virtually guarantees no upset below threshold but results in an overestimate of error rate if the cross section is erroneously assumed to be constant at all LETs greater than the threshold LET. Specifying a threshold LET at a fraction of the saturated cross section attempts to approximate the error rate better, but it introduces an arbitrary factor (to account for the slope of the

cross section vs. LET) and an assumption that the saturated value is known and/or achieved with the highest LET test ions.

The best way to calculate error rates is to use the full curve of cross section vs. LET, which may be available from the parent test organization^[1], and integrate it over all angles and all ions of various LETs. But even this method, which involves the use of a computer, relies critically on what assumptions are made about grazing ion impacts and the dimensions of the device cell's sensitive volume.

All data are presently divided into two tables. Table 1 has been revised to include all SEE (soft error) data for both MOS/CMOS and bipolar devices. Table 2 exhibits data for "Latchup Tests Only". All data listed here represent a substantial abbreviation and ignore statistical features altogether. LET limits are for nominal effective values without correction for degradation that can occur when an ion traverses device overlayers. Gold data, in particular, are seldom as damaging as one would expect on the basis of nominal LET and such data are labeled when known, and Au testing is usually not recommended. SEE tests use a dynamic nominal bias (often 4.5 or 5.0 V); latchup tests are usually performed at the maximum value of the nominal bias range (e.g. 5.5V) -- a condition usually (but not always) enhancing the possibility of latchup. Reported data were taken at room temperature or ambient temperature; higher test temperature measurements may exist for some parts. In some instances, data on transients is noted, which may or may or may not impact electronics down the line. Hence, a system designer interested in a specific part is again urged to contact the appropriate test organization for further information.

Users are cautioned that manufacturers (Appendix I defines manufacturer abbreviations) may often change their process, and resultant SEE susceptibility, without changing the part number or notifying tester organizations. Hence, a test of flight parts is always a good policy.

Trends & Limitations

Trends and device comparisons in the recent data are offered in the "Remarks" column of Tables 1 and 2 and in the following section. However, the organized tabular format is designed to facilitate comparisons. Special studies (such as variation of SEE response with temperature) or a comparison between high energy (GANIL) heavy ion data and that from the lower energy Berkeley 88-inch cyclotron and BNL Van de Graaff are beyond the scope of this presentation. In addition, test data for the whole class of catastrophic failures of power transistors, both MOSFET and bipolar, has recently been organized by Nichols under a substantially different format.

Some colleagues have commented that a measure of the shape of the cross sections vs. LET might be useful-- such as given by a tabulation of the Weibull parameters. Others point out that it may be more difficult to assure that such parameters are properly derived and applied than it is to calculate SEE rates directly from known (and readily available) experimental cross sections.

Program managers concerned with critical system reliability issues will ultimately need an appropriate set of cross sectional data to assess statistical features and focus on specific answers. Ballpark estimates will also have a place, however, by helping assure that expensive experiments are limited to only critical SEE issues.

An Evaluation of SEE Data

Microprocessors

JPL tested a large body of SEE data for microprocessors this year, mostly with 16-bit and 32-bit capability. Soft error thresholds are consistently low for all high-capability machines, with LET(th) ranging from approximately 1 to 10 MeV/(mg/cm²). Important exceptions are two 16-bit devices by Marconi (GEC-Plessey), using their well-established SEE-resistant SOS technology. Most microprocessors are not very susceptible to latchup although there are exceptions (e.g. the IDT R3000 and R3000A.) The Intel CHMOSIV technology is marginally susceptible to latchup, whereas its earlier CHMOSIII technology was not. There is a very large set of data from ESA and Harris on the R3000 and R3000A RISC developed by many manufacturers.

Questions raised last year regarding the best approach to microprocessor testing remain open. The purists argue that static testing of known registers in a known state is the best approach to understanding SEE effects. JPL presently pursues this view and has demonstrated that not all elements of a microprocessor are equally SEE-susceptible. The pragmatists claim that testing with dynamic programs (the more the better) will usually show that static tests provide an unrealistic worst case.

Some data taken by European groups at GANIL, the higher-energy (10 to 100 MeV/amu) cyclotron in France, are available. The results suggest that these ions, which are more representative of interplanetary cosmic rays, are more damaging than the familiar lower-energy (2 MeV/amu) ions provided by Brookhaven's Van de Graaff and Berkeley's 88-inch cyclotron. Direct comparisons between energy regimes are few.

It will also be observed in Table 1 that there are data for several controllers and processors of various types. They have similarly low soft error thresholds [$< 10 \text{ MeV/(mg/cm}^2)$] and varying latchup susceptibility.

^[1] JPL data, including more recent results, may be accessed directly from JPL's computer data base, RADATA.

Analog-to-Digital Converters (ADCs)

There are several data sets for ADCs and data for two digital-to-analog converters (DACs). Much of the data were taken by JPL in a quest for the least SEE-susceptible 12-bit ADC. The MAXIM devices were clear standouts in this subcategory, but one observes that a completely hard ADC or DAC is a rarity. This is one device type where knowledge of how the device ties in with the system is an all-important consideration in assessing its ultimate suitability.

Static RAMs (SRAMs)

There is much new data to add to the accumulation for SRAMS--with device sizes up to 4 Mbits. All devices employ variations of CMOS technology this test period, and SOI and SOS offer markedly superior resistance to soft errors and latchup. Epi technology (where the epi layer is less than ~10 microns thick) is a good guarantee against latchup but offers no significant advantages against soft errors. A tendency toward stuck bits was observed in the 0.5 micron feature-size Hitachi 4 M SRAM.

Other RAMS

ESA tested a large set of 4M DRAMs and observed a consistent very low soft error threshold typical of this device function. Some non-volatile RAMs were tested-- with two Ferroelectric RAMs (FRAMs) for the first time. Some bipolar and CMOS PROMs exhibited relatively high SEU thresholds, but one should note that PROMs are occasionally susceptible to latchup.

Gate Arrays & Bus Controllers

Several gate arrays, configured in different ways, were tested. It is difficult to sort out the large variability in soft error threshold-- even among devices made by the same manufacturer. It is encouraging that no cases of latchup were reported.

Latchup Data

Tests for latchup only are much easier to set up than those designed to measure soft errors as well. Such data are given separately in Table 2-- primarily for devices with different variations of CMOS technology. It has so far held true that bipolar devices will not latchup with heavy ions. However, latchup has occurred in bipolar devices when exposed to high intensity gamma pulses, and the requisite pnpn parasitic structure exists.

The LET thresholds listed in Table 2 are for latchup only, and cross section data is rarer because of the difficulty in obtaining repeat measurements where catastrophic burnout and overheating may occur. Also presented are data for GANIL which appears to have a devastating effect-- including latchup in several devices with epi technology. Once again a need to compare data on identical parts for both high energy GANIL ions and lower-energy ions is manifest.

JPL was able to employ Cf-252 usefully for the first time-- as a screen to reject some ADCs because of latchup. It is cautioned, however, that Cf-252 can never be used to pass a part for latchup because of the possibility that the fission ions do not have adequate range to maintain an adequate LET while generating a funnel at the well-substrate junction.

Latchup observed by MIT-Lincoln Lab in the NSC driver/receivers 26C31 & 26C32, a pair of linear devices, is explained by Sferrino [9]. He notes that the chips have tristated digital outputs, comprising an npn and pnp transistor in series—the familiar structure for latchup paths. This result suggests that other transistor arrangements, such as siliconcontrolled-rectifiers, may be susceptible to latchup.

Conclusions

The new data presented here can be combined with data given in References (1, 2, 3 and 4) to develop certain generalizations useful for protecting flight electronics from SEE. Hard technologies and unacceptably soft technologies can be flagged. In some instances, specific tested parts can be taken as candidates for key functions-- such as microprocessing or memory. As always with radiation test data, specific test data for qualified flight parts is recommended for critical applications. Calculations of accurate SEE rates will require the assistance of a computer code, a well-defined environment [in terms of flux vs. LET] and a complete device characterization [cross section vs. LET at the appropriate temperature.] Evaluation of catastrophic effects requires its own statistical treatment, in which flares are considered. The recent concern of JPL and others with power transistor burnout and single event gate rupture is beyond the scope of this compendium.

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	Appendix I - Manufacturer Abbreviations	TOS TRW	Toshiba TRW Inc.
ACT	Actel Corp.	UTM	United Technologies Microelectronics Center
ADA	Advanced Analog	WAF	Waferscale
ADI	Analog Devices Inc.	XIC	Xicor Inc.
ALS	Allied Signal	XIL	Xilinx Corp.
ALT		ZOR	Zoran
	Altera Corp.	ZYR	Zyrel
AMD	Advanced Microdevices Corp.		
ATM	Atmel		
ATT	American Tel & Tel		Appendix II - Test Organizations
BUB	Burr-Brown Research		5
CRY	Crystal Semiconductor Inc.	Α	The Aerospace Corporation; El Segundo, CA
CYP	Cypress Corp.	BPS	Boeing Physical Sciences Research Center, Seattle
DAT	Datel	CLM	Clemson University; Clemson, SC
DDC	DDC ILC Data Device Corp.	CNES	Centre National d'Etudes Spatiales; Toulouse, France
EDI	EDI Corp.	ESA	European Space Agency several facilities
FER	Ferranti	GD GD	
FUJ	Fujitsu Ltd.		General Dynamics
GEC	GĚ	GDD	NASA Goddard Space Flight Center; Greenbelt, MD
HAR	Harris Corp., Semiconductor Div.	GE	GETSCO, Philadelphia
HIT	Hitachi Ltd.	HAR	Harris Semiconductor, Melbourne, FL
HON	Honeywell Inc.	HON	Honeywell, Clearwater, FL
IBM	IBM	J	Jet Propulsion Laboratory (JPL); Pasadena, CA
IDT	Integrated Device Technologies, Inc.	JН	John Hopkins Applied Physics Laboratory; Laurel,
INM	INMOS Corporation		MD
INT	Intel Corp.	LIN	Lincoln Laboratories, M. I. T.; Cambridge, MA
LDI	Logic Devices Inc.	MMS	Matra Marconi Space; Vélizy, France
		NASA	NASA
LTC	Linear Technology Corp.	NRL	Naval Research Laboratories, Washington D. C.
LSI	LSI Logic Corp.	R	Rockwell International (Anaheim, CA)
MED	Marconi Electronic Devices	SSS	S-Cubed, San Diego
MCN	Micron Technologies	TRW	TRW Space and Defense Sector (Los Angeles, CA)
MIT	Mitsubishi		cpare and
MMI	Monolithic Memories Inc.		
MOT	Motorola Semiconductor Products Inc.		Appendix III – Test Facilities
MPS	Micro Power System		
MTA	Matra Harris SemiconductorMXM MAXIM	88-in.	= 88-inch cyclotron, Lawrence Berkeley
NAT	Natel Engineering		Laboratory
NEC	Nippon Electric Corp.	BNL	= Tandem Van de Graaff, Brookhaven National
NSC	National Semiconductor Corp.	שאום	Laboratory, Long Island, NY
OWI	Omni-Wave, Inc.	Cf 252	= A Cf-252 fission source
PFS	Performance Semiconductor Corp.	ESA	
PLS	Plessey Semiconductors		= European Space Agency several sites
PMI	Precision Monolithics, Inc.		C = Cyclotron for Heavy Ions; Caen, France
RAY	Raytheon Co., Semiconductor Divison	HAR	= Van de Graaff at Harwell, England
RCA	Radio Corporation of America	IPN	= Tandem Van de Graaff, Institut de Physique
RTN	Ramtron	~ ~ ~	Nucleaire; Orsay, France
SAM	Samsung	UW	= Tandem Van de Graaff, University of
SEI	Seiko		Washington, Seattle
SEQ	SEEQ Technology Inc.		
SGN	Signetics Corp.		
SIE	Siemens Inc.		
SIL	Siliconix		References
SIP	Sipex		
SLG	Silicon General		K. Nichols, W. E. Price, W. A. Kolasinski, R. Koga, J. C.
			J. T. Blandford, A. E. Waskiewicz, "Trends in Parts
SNL	Sandia National Laboratories		tibility to Single Event Upset from Heavy Ions," IEEE Trans.
SNY	Sony Corp.	on Nuc.	. Sci., <u>NS-32</u> , No. 6, 4189 (Dec. 1985)
SOR	SOREP Teledine Chievalonics	503 T	77 371 1 7 0 0 1 1 37 9 9 1 7 77 1
TEL	Teledyne Crystalonics		K. Nichols, L. S. Smith, W. E. Price, R. Koga, W. A.
TIX	Texas Instruments Inc.		uski, "Recent Trends in Parts SEU Susceptibility from Heavy
TMS	Thomson Military & Space, France	ions , i	EEE Trans on Nuc. Sci., NS-34, No. 6, 1332 (Dec. 1987)

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- [9] Vince Sferrino, MIT Lincoln Lab, private communication.

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Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise, does not constitute or imply its endorsement by the United States Government or the Jet Propulsion Laboratory, California Institute of Technology.

TABLE 1. SEU DATA - 1991-1992 (MOS & BIPOLAR DEVICES)

Effective LET** Bits Threshold
¥, -
1
1
ı
Test data taken with low energy Harwell Tandem Van de G. gives much smaller cross sections than preceding data.
-600
510 of 752
ı
1
all 3 chips
·
ı
- 150(Au)
>>2.5
272 3.5±1
1
varies <1.7
varies
~1300
~1300
736 (23 reg)
1
~2300 total ~3[1% sat]

^{*} See listing of abbreviations in Appendix I.

** LET is Linear Energy Transfer = the density of fonization along an lon's path in MeV/(mg/cm²). The cosine law for beam angle is applied where valid to obtain "effective" LET.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix II.

**** Unless otherwise noted, the cross section (upsets/fluence per device) is given for 240-380 MeV Kr or Br at normal incidence, having an LET=36 to 40 MeV/(mg/cm²).

TABLE 1. (Cont'd)

Remarks	IEEE92 Workshop Record, p1.	No LU>27. Harboe-Sorensen 92IEEE Workshop	LU=27. Harboe-Sorensen 92IEEE Workshop	No LU>27, Harboe-Sorensen 92IEEE Workshop	No LU>60. Harboe-Sorensen 92IEEE Workshop	10/92. See Table 2. LU(th)=24 to 37.	92IEEE Workshop. 1=register test	92IEEE Workshop, 1-register test	Dufour, 92IEEE Workshop. (1)=MPY test program;	(2)=RAM test. LU=31; 1E-4 cm ² .	LU=13.5; 1E-4 cm ² .	JH also reports that an experimental version of the above, having a different substrate, exists with No LU>120. (See J. Kinnison, IEEE NS Dec 91, p 1398). Availability not known.	No LU>>38, but a 17 µm epi std. production part	latched up easily. M. DeLaus - 1/91.	LU=12; 2E-5 cm ² . Harboe-Sorensen IEEE NS Dec 92,	p 441. See above.	1291. No LU>110.	1/92, No LU ₅ 89.	2/92.	10/92. DC: 9142 No LU>>37. WP-02	No LU5100, 10/92	LU=7;1.3E-5 cm ² . [1]=bipolar, but LU raises questions	of possible CMOS also. DC: 9142 & 9222 WP-02. 10/92	12/91. See Table 2: J: No LU>120. 11/92	2/91. Fl lon only.	7 & 9/91. No LUI>175. See Table 2.		11/92	11/92	No LU>>37. 10/92 DC: 9210	11/92 See Below. No LU>120 at 80° C.	Earlier DC is latchable.	11/92 LU(th)=30. See above.	9/91. No LU>110.	9/91. No LU>110.	11/92. No LU>120.	11/92. No LU-120.	7/91. LU LET<<40.	7/91. LU LET<<40.	9/92, No LU>104	No LU-100. 1/92
Facility***	BNL	BNL	BNE	BN	BNF	BN	M	N.	GANIL		BNL	Innison, IEEE	BNL		<u>K</u>		BNL	BNL	3	BNL	88-in	BNL		88-in	₹	BNL &	88-in	BNL	BNF	BNF	BNL		BNL	88-i-	88-jr	BNF	BN.	BN	BNL	BNF	88-in
Section Per Bit (sq µm)	1	×100	100	7	200	20[LET=24]		1	•		ı	120. (See J. Kl			300			1	ſ		i	ı		1	1	1		1	ı	1	ı	,	1	ı	1	ı	1	ı	1	1	1
Device Cross Section (cm²)***	×1E4	1	•	ı	ı	1	1E-2 ^[1]	1E-2[1]	4E-4	2E-2	5E-3	ists with No LL	3E-4		ì		5E-5	4E-5	>2E-4	1.4E-4	2E-4	3.2E-4		1E-3	>1E-4[LET=10]	2E-4[8 MSB's]		×2E4	×2E-4	8E-5	×1E4		1	1	ı	>5E-4	>1E-3	1	•	1	5E-4
Effective LET** Threshold	÷	\$	æ	ę	ģ	4	က	co	7	7	5	substrate, ex	7		80		413	₹	\$	ষ	ধ্ব	6 3		7	\$	9		ន	ន	2	9		9	Ş	2	2	€,	\$	\$	₹	6
Bits	006	1024 (32 reg.)	1024 (32 reg.)	1024 (32 reg.)	1024 (32 reg.)	all 640	varies	Varies			1	naving a different	, 1		531		16 tested	ı	ı	1	ı	ı		t	1	ı		ı	ı	ı	1		1	,	ı	1	1	ı	ı	ı	1
*.' ±	¥	פֿ	ISI	PFS	뫐	¥	MOT	MOT	TIX(Fr?)	•	ADİ	te above, t	ADI		ADI		¥.	£	ADI	¥	£	ADI		Sd≅	ADI	ADI		HXH	MXM	HAR	HAH		HAH	AD	ADI	ADI	MXM	BOB	BUB	ADI	dis
Technology	CHMOS III	CEMOS V	HCMOS		VAdv. CMOS	CHMOS IV	CMOS/epi	CMOS	CMOS		CMOS/epi commercial	perimental version of the	CMOS/epi 13 µm		CMOS/epi 12.5 µm		Hybrid RH CMOS	CMOS	Bipolar (I 2 L)		BICHOS	Ξ		CMOS	CMOS	CMOS		BICMOS	Bipolar/CMOS?	CINOS	DC9205		DC9028	BIMOS	Bipolar (Two chip)	BIMOS	BICHOS	Bipolar/CMOS	Bipolar/CMOS	BICMOS	CMOS Hybrid
Function	DMA Cort. 32-bit	FP Accel. Coprocessor CEMOS V	FP Accel. Coprocessor HCMOS	FP Accel. Coprocessor	FP Accel, Coprocessor VAdv. CMOS	Coprocessor	FP Coproc. 32-bit	FP Coproc. 32-bit	DSP		OSP	also reports that an ex	DSP		DSP		Resolver Dig. Conv.	8-bit DAC	8-bit DAC	12-bit DAC	12-bit DAC	8-bit ADC Flash		8-bit ADC Flash	8-bit ADC	12-bit ADC		12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC		12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	14-bit ADC	16-bit ADC
Device	62380	_					68882	68882	TMS320C25		ADSP2100A	Ę	ADSP2100A		ADSP2100A		HSRD1056	DAC8408	AD558	PM7545	DAC8412	AD9048TQ		MP7684	AD7824	AD7672B		MX7672	MX7572	HI574	HI674ALD		HI674ASD	AD574A	AD674A	AD674B	MX674A	ADC574A	ADC674	AD7872	HS9576RH
Test Org.****	GDD	ESA	ESA	ESA	ESA	H	CNES	CNES	•		- -		NR.		ESA /		7	SSS	BPS	NOH	<	NO P		<	BPS	7		7	-	NO.	7		7	7	7	7	7	7	7	7	٧

TABLE 1. (Cont'd)

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	Remarks	92IEEE Workshop Kinnison	92IEEE Workshop Kinnison. "Ninitatch"	LU=38. 9/92. Compare Table 2	McNulv- (FEE '91	111-15-1E-3 cm ² 19/09	LU=10: 1E-4 cm ² , 12/92	UNDER US 6/90 PAS 011-WHEN US AN ENTER US	IEEE NS 6/92 pd50 [1]=Will variable R	5/91. No LU>90 up to 125 dea C.	DC=? See above.	No LU. W. Newman 10/91, [1]=Rad Hard CMOS/SOS	3.0 um technology	3.0 um technology	1.5 um technology	6/92. Development SRAM. No 115-115.	1/91. No LU reported IEEE 91. Compare '87. Astospace data	[1]=Factor of 100 lower for high R. No 115-100, 6/92	No LUS-100, 7/91	LU(th)=23; 1E-2 cm ² Dufour, 92IEE Workshop	7/92 Multiple upsets	Date Code 9133	<5/91. DC8116 No LU>26. Possible multiple	errors/strike. (1)=Worst case all 1's	Date Code 9125. [1]=at 10% of aat. See Table 2.	Date Code 9101 (1)= Worst case all 1's [2]=at 10% of sat.	(1)=low current resistor process. [2]=at 10% of sat.	IEEE91. No LU>100. Multiple errors/strike. A high	resistivity DUT: SEU cross=~1E-2 cm².	9/91. No LU≽110. No date code.	8/91. LU=50; 4E-4 cm2. [1]=at 10% of sat.	Compare earlier CNES data.	1992. Engr. sample	9/91. No LU>50. R. Ecoffet	12/90. 1µm.; No LU at LET=116		Date Code 8933	Date Code 9151	No LU>100. 10/92	LU=8; 8E-3 cm ² , 10/92	LU=45; 2E-5 cm ² , 10/92	LU=55; 2E-5 cm². 2/90 (Corrected)
	Facility	BNL	BNL	BN	BNL	88-in	88-in	. I	8	8	BNL	BNL	88-In	88-in	88- 	BNF	M	88-In	88-in	GANIL		<u>R</u>	M		Nd	PN	M	88-in		88-In	M		M	M	BNC;	GANIL/IPN	N <u>d</u>	M	88-In	88-In	88-In	88-In
Cross Section Per Bit	(mri be)	ı	í	94	ı	8	8	8	8		ı	1	2 @ LET=75	5 @ LET=75	2 @ LET=120	No upset	100	ı	1	ı					1	1	1	1		1	300		1		8		ı	t	ı	•	ı	
Device Cross Section	(cm²)	8E.4	3E-3	4.2E-3	5E-6 @ LET=24	8E-3	Ā.3	ı	ı	ı	ı	ı	1	ı	ı	No upset	1	~-1[1]	6:0	9.0		0.5	0.6[1]		1.8	2.0	2E-3	7		2E-2	0.2		 1:0	80	t		0.2	ı	8E-2	0.1	0.2	8E-2
Effective LET*	Diouseuu	~	o	3.5	9	'n	8	*	25 to 40	6	28	≯138	9	8	9-	>115	۲-	£.	က	7		4.5	~		611)	5.2	₹/4	4		8	2.5; 10[1]		6[10% sat]	9[10% sat]	NO.		우	*1 *	4	က	Ţ	m
Š		64x9	512x9	1Kx9	2Kx8	2Kx8	2Kx8	2Kx8	2Kx8	8Kx8	8Kx8	Æ ¥	16Kx1	2Kx8	64Kx1	64Kx1	32Kx8	256Kx1	32Kx8	32Kx8		1 % 1	128Kx8		128Kx8	128Kx8	128Kx8	128Kx8		128Kx8	8Kx8		32Kx8	8Kx8	9Kx8		9Kx8	9Kx8	2Kx8	8Kx8	128Kx8	128Kx8
3	. Wall	NSC	NSC	TQI	¥	<u>LOI</u>	CYP	NO.	HON	HON	임	HAR	MED	MED	MED	WB.	<u> </u>	ZS ¥CS	S S	<u>₹</u>		NCN NCN	MCN		NC.	MCN	NCS NCS	NCN NCN		₹	MTA	į	MTA	MTA	MTA		MTA	SE	ᆸ	ᄓ	MOT	SNY
T de se	1 actionogy	CMOS/epi	CMOS/epl	CMOS/epi	CINOS	CMOS/NMOS	CMOS/NMOS	CMOS[1]	CMOS[1]	CMOS/SOI DC9029	CMOS/epi	Std Cell [1]	CMOS/SOS	CMOS/SOS	CMOS/SOS	CMOS/epi	NMOS/CMOS	CMOS/NIMOS	CMOS/epl	CMOS 2M-2P		CINOS	CMOS/epi		CMOS	CMOS/epi	CMOS	CMOS/epi NMOS		CMOS/epi [new version]	CMOS/epl [12 µm]		SCMOS	SCMOS Final process	SCMOS/epi		CMOS/epi	SOI	CMOS(V)NMOS	CMOS(V)NMOS	CMOS/NMOS	CMOS/NIMOS
	Lancing	5 <u>F</u>	<u> </u>	FIFO (10 µm)	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM		SRAM	SRAM		SRAM	SRAM	SRAM	SRAM		SRAM	SRAM			SRAM	SRAM			SRAM	SRAM	SRAM	SRAM	SRAM
edive C	1	54AC708	74AC725	7202RE	HC5517A	L6116	CYPC128A	HC6116	HC8216	HX6364	HC6364	TS054	MA6167	MA6116	MA9187	IBM6401	EDH8832C	MT5C256	MT5C2568	MT5C2568C	4	MT5C1001	MT5C1008		MT5C1008	MT5C1008	MT5C1008	MT5C1008		MT5C1008C	HMS65641		HM65656	HM65664	HMT-65664		HM65641	TS4H6408	IDT7052	IDT7164	MCM6226	CXK581000P-10L
Test	5	亏	동	GDD	CLM CLM	⋖	∢	HON	HON	7	PN PN	HAH	ESA	ESA	ESA	7	ESA	∢	4	MAS		CNES	CNES	!	CNES	CNES	CNES	⋖			CNES	e i	CNES	CNES	NASA		CNES	CNES	⋖	⋖	⋖	ک ح

TABLE 1. (Cont'd)

																														⊞².	75									
Remarks	LU=30; 5E-5 cm ² . 10/92	9/92. No LU>90 Stuck bits seen.		No LU-82. 4/92		LU(th)=25; 1E-4 cm ² dynamic test. 4/92	No LU>82. 4/92	No LUS 50 RADECS 91	No LUS-40 RADECS91	No LU≻40 RADECS91 [1]=Engr. sample.	See also Table 2 & below.	No LU>100. 3/92	No LUS 50 RADECS 91	No LUS-40 RADECS91	No LUS-40 RADECS91	No LUS-40 RADECS91	No LUS-40 RADECS91		(1) = SRAM configuration.	(1) = EEPROM configuration.	6/92. LU LET<<30	6/92. LU LET=45.	Date Code 9025	Date Code 4039	DC 9032. Table 2	No LU-100. 5/91 "=READ, "=WRITE	Compare following.	Perm. fall @ LET=60 IEEE92 Workshop p1	92IEEE Workshop Dufour 7/92	92IEEE Workshop Dufour 7/92 LU(th)<32; 3E-4 cm ² .	LU=58; 2E-4 cm ² . 92 IEEE Workshop Dufour. 7/92.	Compare earlier data.	No LU>87. Dufour 92IEEE Workshop	No LU>73. 7/92. Compare to next.	No LU>120 7/92 Compare above.	564 Ho 11.138	Main 140 Loy 120.	NO LUSTZ4. UMOUT SZIEEE WORKSROP	No LU>87. 7/92 FSC design	No LUIS87, 7/92 FSC design
Facility***	88-In	BNF		BNL		BNL	BNL	M	M	M		88-in	Nd	M	M	M	N.		Z	M	Cf-252	BNF	Nd	NO.	. A	88-in		BNL	GANIL	GANIL	GANIL		GANIL	BN	GANIL	Na		GANIL	NE S	BNL
Cross Section Per Bit (sq µm)	1	8		9		ষ	12	8	12	8		,	\$	8	8	8	8		ı	ı	ı	ı		ı		1		ı	1	1	1		nly) –	1	•		ı	ı	ı	•
Device Cross Section (cm²)***	0.15	1.25		0.11		0.24	1	ı	ı	ı		~2(4.5V)	1	ı	1	1	i	9	0.32	1	2E-4(dyn.)	3E-3[dyn.]	•	1		1E.4*	4E-4**	5E-3	0.2	5E-2	35.4		3E-5 (peripherals only)	1	7E-6		ı C	9 H H	1.5E-5	XF.5
Effective LET** Threshold	60	-1.5		14		<0.5	7	7	? -	7-		ey	7	7	7	7	7	5	۲۰۰۰	×114 ⁽¹⁾	**	÷	254	7	\ 1	~15*	:5	3.4(write)	432	54	8		8 3E	57*	ಹ	S	3 ;	2 •	∞ .	4. 5
BHs	128Kx8	\$12Kx8		1Mx1		1Mx1	4Mx1	4Mx1	4Mx1	4Mx1		1Mx4	4Mx1	4Mx1	4Mx1	4Mx1	4Mx1		8KX8	ВК хВ	2Kx8	512x8	32Kx8	32Kv8	32Kx8	32Kx8		32Kx8	8Kx8	8Kx8	2Kx8		8Kx8	8Kx8	8Kx8	1847739	75/125	1	ı	1
Mr.*	SNY	토		E01		NEC	불	EU.	불	MCN		MCN	NEC	SAM	SE	TRIS	TOS		PLS	PLS	HTN	MTN	SEO	ATM	ž	SEO		SEQ	CYP	WAF	HAR		RAY	SGN	SGN	1	E 5	¥ į	MIA	MITA
Technology	CMOS/NIMOS	Hi-CMOS/epi 0.5 µm	feature	í		ı	•	CMOS	CMOS	CMOS[1]		CMOS/epi 7 micron	CMOS	CMOS	CMOS	CMOS [EPIC]	CMOS		CMOS/SNOS	CMOS/SNOS	CMOS	CMOS/epi	CMOS/FG	CMOS/EG	CMOS/FG	CMOS/epi		CMOS/epi	CMOS/FG	CMOS/FG	CMOS		Bipolar	Bipolar	Bipolar	CHOCkeni			CMOS/epi	CMOS/epi
Function	SRAM	SRAM		DRAM		DRAM	DRAM	DRAM	DRAM	DRAM		DRAM	DRAM	DRAM	DRAM	DRAM	DRAM		RAM Non-vol.	RAM Non-vol.	FRAM	FRAM	EFPROM	EFPROM	EEPROM	EEPROM		EEPROM	EEPROM	EEPROM	PROM		PROM	PROM	PROM	Due Controller		MACS Bus Com.	ASIC (Bus)	ASIC (Bus)
Device	CXK581001	HM628512		EDI 41024C100QB	Mosaic	MDM100TMB	Aosaic MDM1400G	MB814100-10PSZ	HM514100ZP8	MT4C1004C		MT4C4001	D424100V-80	KM41C4000Z-8	HYB514100J-10	TMS44100DM-80	TC514100Z-10		7008	P10088	FMx1408	FMx1208	28HC256	28HC258	X28C256	DM28C256		28C256	CY7C261-55	WSF57C49B	HM6617		R29793DM	82HS641A	82HS641	I ITMESS			Bus Cont.	Serial Cont.
Test Org.****	×	CDD		æ		Œ	<u>ac</u>	ESA	ESA	ESA		⋖	ESA	ESA	ESA	ESA	ESA		CNES	CNES	7	7	CNES	CAES	CNES	⋖		GDD	Ş	SH	MMS		MAS	GDD	MAKS	-		NEWS S	ago	COD

TABLE 1. (Cont'd)

	1		.87.			=	:																		i					1											l
	Chamis ESA Cant 4400 M. 111 co	Maria Con Coll. 11/30 No LUSES.	No LUSSE. Durour Sziere Workshop See JPL data '87.	7/91 [1]=D flip-flop [2]=RAM config.	LU(th)=5; 5E-3 cm2 DC9110 & 9045, 7/92	1991, ACT Il family [1]=C module [~10 PLD-equivalent	08fe8.] [2]=S module, No 1115-150, Con Dat 9	See Ref. 8 [1]=Process Prog. G A No [1]>120.		See Ref. 8 No LUS 80.	The state of the s	See hell o no LUSIZU. 3/32 D F/F's; SRAM	604 21 10-1-1		6/91 [1]=Van de G.	6/91. Latchup.	No LU-120, 12/92	LU(th)<<26, 12/92	Wih = 19: KE. A 19:09		LO(m)=25; 3E-4 cm* Die similar to below.	LU(th)=25; 3E-4 cm ² Die similar to above.	6/92	6/92	6 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4 4	LU(m)=25; 2E-3 cm*.	No LU>100. 5/91 Compare preceding.	LU(th)=25; 5E-4 cm ² .	No LU>32. Dufour, 92 IEEE Workshop	National Contraction	NO LOSSE. Dulour, SE IEEE WORKShop	No LUNTIO. Durour, 92 IEEE Workshop	7610	76/7	292	No LU>140. Dufour, 92 IEEE Workshop	No LU>140. Dufour, 92 IEEE Workshop	No LU>>37. DC8942 Wn-02 10/92	No LUS 100, 1/91	No LUS-100. 6/92	9/91, No LU⊳110,
Facility	INAG	CANE	CAINE	E-92	BNL	88-in		88-in		88-In	RP.In	5	UADIA		HAH[1]	CI-252	BNL	BN	88-In			BNL BNL	88-In	88-in			BN L	BN	GANIL	CANII		GANIL 90 in	1110	5 5	\$	GANIL	GANIL	BN	88-In	88-In	88-In
Cross Section Per Bit (ser 11m)		!	4000141	Islanzi	1	300[1]	8000[2]	£		2	Ę	3	1	l	ı	ı	1	,	1	ı	Ì	1	ı	ı		ı	ı	ı	-	2500	250	500	2000		ı	ı	1	1	1	,	1
Device Cross Section (cm²)***	2E-3	55.3	}	ı	1	-1		;		1	•		3.6E-6/eat)	2E 6(nd)	3E-0(881)	4.2E-5	ı	1	1	75.6	. u		ZE-3	2E-5			<1E-7	# :	1E-3	F 2	, m	3 2	.2E.5/1 ET10)	25-5(1 ET-40)	25-3(EE1=10)	6E-6	1	8.6E-5	5E-6	4E-5	2E-3
Effective LET** Threshold	<5.5	8	8	i	1	30[1]	2 [Z]	8		\$	18		4.0	α	.	. :	> 120	1	10	10	· w	, •	.	4	4		<u> </u>	വ	_	7	627	, se				3	>140	ន	°70	ន	ę
B)		:	Maitical		, ,	200		38K gates		Test Chip	Test Chio	-	ı	ı		ı	ſ	ı	1	ı	ı	}	ı ·		ı		ı	1		⋖*	P	~ ~		ı		Ļ	ı	Octal	Octal	∞	ı
Mr.	E	MTA	HON	ķ	, to	¥		ड		₹	MT		ALT	ALT	VE)	אם מר מר	L	CYP	CYP	CYP	MM	ANO		¥	10	<u> </u>			¥	XI	MOT	MOT	NSC	SGN	1	2 5	2	NSC	¥	HAR/GE	SLG
Technology	Bipolar	i.) CMOS	RICMOS III	CMOS	Cline (4 9	ביין און ולשיביים	rearure)	CMOS/epl rad-hard	(1.5 µm feature)	CMOS/ept red-hard	CMOS/epi rad-hard	(1.0 µm feature)	1	•	•	SCHOOL		CMOS	CMOS	CMOS	CIMOS	Binolar	o polor	oipoiar	CMOS	CMOS	CMOS	ET I	3	LSTIL	bipolar/ECL	TTL(LS)	bipolar	bloolar	FACT	EACT	25		CMOS/HCT	CMOS/HCT	bipolar (&1 JFET)
Function	ASIC (Bus)	Gate Array (Memory Plan.)	Gate Array	FPGA	A COL	5		PPGA[1]	•	Y S	PPGA		Prog. Logic Dev.	P.C	PLD	. IVd		rat.	PAL	PAL	PAL	PAL	DAI	781	EDAC (32-bit)	EDAC (32-bH)	EDAC (32-bit)	EDAC.		D. FF	出る	J-K/FF	Timer	Timer	Counter	DEC		D-Laten	Latch	Counter	WM
Device	-		HR1060	XC3090	A1280			LHM10038Q	900	3	RA20K		EP310	EP600	20RA10Z	22V10C-10	SOVIOR JERNIN	201400	22V 10IS	22V10	22V10	22V10A	22V10A	501	IDT49C460	IDT49C460	ı	54l S630		54LS74A	MC10531	541.5112	555	555	54ACT163	54ACT374	EAACTOSTS	SACIGALS S	54HCT373	54HC1393	PWM1526
Test Org.	CNES	E	오	GDD	⋖	;	•	⋖	•	ς .	∢	į	ESA	ESA	ESA	GDD			₹ }	<u> </u>	8	⋖	⋖	:	IBM	⋖	W.	MWS		MINS	SE SE	⋖	BPS	BPS	SWE S	MMS	3	5 •	< 4	«	7

TABLE 2. LATCHUP TEST ONLY (1991-1992)

Test				i	Š	Effective LET**	Device Cross Section		
÷	Device	Function	I echnology		aus	Inreshold	(cm-,)	Facility	нетака
Ŧ	645007	MicroP (16-bit)	CMOS/epi	झ	ı	K	1	BNL	1750A CPU.
3	68020	MicroP (16-bit)	CMOS/epi	MOT	1	3246	1	BN BN	4/91
<	HS82C88	Bus Cont.	CMOS	HAR	1	æ	4E-6	88-in	12/91
⋖	HS82C59A	Priority Int. Controller	r CMOS	HAR	•	9	2E-3	88-in	1291
⋖	HS82C52	Ser. Cont. Interface	CMOS	HAR	ı	8	2E-5	88-In	1291
HAR	H3000	MicroP (32-bit)	CMOS?	TOI	ı	4.8	1	BNL	May 91. Table 1. MPS RISC. D. Vail (HAR)
HAH	R3000A	MicroP (32-bit)	CMOS?	IDT	ı	88	1	BN	May 91. Table 1. MIPS RISC. D. Vail (HAR)
HAR	R3000A	MicroP (32-bit)	CMOS?	PFS	•	8	1	BNL	
HAH	H3000	MicroP (32-bit)	CMOS	ısı	1	ន	1	BN	
NA.	L64801	MicroP (32-bit)	CINOS/epi	ısı	1	16.5	4E-3	GANIL	SPARC, Dufour, 92 IEEE Workshop
MAS	L64811	MicroP (32-bit)	CINOS	ısı	ŧ	8.2	5E-2	GANIL	SPARC, Dufour, 92 IEEE Workshop
SA SA	L64814	F.P.U. (32-bit)	CMOS/epi	ड	1	9	2E-3	GANIL	SPARC. Dufour, 92 IEEE Workshop
WW	1800	Transputer (32-bit)	CNOS	X	•	\$	>1 E-4	GANIL	Dufour, 92 IEEE Workshop
4	WE-DSP32C	DSP	CMOS	ATT	•	1	1.7E-2	88-in	June 1992
: -	320025	dsa	CMOS/en	TIX (France)	ı	36 @ 1E5 lons/cm ²	•	BNL	LU=26 at 125 deg. C 5/91. DC 8939. Compare to earlier data.
•		ì	L			,			See Table 1.
Ξ,	320025	DSP 6 um epi	New CMOS/epi	ΧĽ	ı	8	,	BNF	92 IEEE Workshop, Kinnison, 7/92. See previous & Table 1.
<	320030	DSP	CMOS/epi 7 um	χĽ	•	£	5E-5	88-In	12/92. Compare to IEEE 91
7	320C50	DSD	CMOS/epi	×	•	69*	,	BNL	6/92
3	56001	DSD	CINOS	MOT	ı	12	ı	BN	4/91. Dynamic test. See also Table 1.
3	ADSP2100A	DSP (16-bit)	CMOS/epi 18 µm	ADI		5	1 <u>E</u> 4	BNF	IEEE NS (Dec 91) p 1398. See below.
SWE	ADSP2100A	DSP (16-bit)	CIMOS/epl	ADI	ı	83	1E-3	GANIL	92 IEEE Workshop Dufour 7/92
픙	ADSP2100	DSP (16-bit)		둪	•	35	ı	BNL	4/90
SAMS	ADSP2100	DSP (16-bit)	CIMOS/epi	ADI	1	~ 30	ı	GANIL	92 IEEE Workshop Dufour 7/92
7	AM29CEPL154	MicroC.	CMOS	AMD	•	9	2E-3	BNL	6/92
CNES	68881	Coprocessor	HCMOS/bulk 1.5 µm	MOT	Custom	\$	4E-3	M	DC 8942 Compare to 68882 below.
CNES	68882	Coprocessor	HCMOS/bulk 1.2 µm	MOT	Custom	12	1F.3	<u>M</u>	DC 9022. compare to 68881 above.
7	80387	Coprocessor	CHIMOS IV	Ħ	all 640	8	3E-5*(sat)	88-in	9/91. *Deduced from INT 80386 - Table 1, CHIROS IV (J; 7/91).
뜅	80387-16	Coprocessor	CHMOS IV	토	all 640	24 to 37	1	BNF	10/92. See Table 1.
GDD	60387	Coprocessor	CHMOS IV	¥	all 640	ಸ	4E-5(sat)	BNF	7/92
7	MP7684/MP7684A	A 8-bit ADC (Flash)	CMOS	San	1	>120	1	BNL	11/92. Up to 125°C.
CNES	TMS8338	8-bit ADC	CMOS (HS13)	TMS	•	~50	5E-4	N	Aug 91 See following entry.
CNES	TMS8338	8-bit ADC	CMOS (HCMOS3)	TIMS	,	12	2E-3	N <u>d</u>	Aug 91 See preceding entry.
⋖	MP7695	10-bit ADC	CHOS	MPS	•	××100	ı	88-in	Jun 92
TRW	ADC87	12-bit ADC	Hybrid? DC: 8920/9128	BUB		? [LET=60]	>>3E-5	BNF	7/92. T.C. Lunn
THW	ADC85	12-bit ADC	Hybrid? DC: 9203	SIP	1	9**	,	BNL	7/92. T.C. Lunn
7	SP7800	12-bit ADC	CMOS	SIP	1	**30	△E4	CI-252	4/92
7	LTC1272	12-bit ADC	CMOS	LTC	1	6	1	Cf-252	10/92
7	HI774B	12-bit ADC	BICMOS	HAR	1	< 30	1	CI-252	10/92 (DC9022)
	- 11-4 an and and and	fathers in Assessment	1					BNF	11/92

^{*} See listing of abbreviations in Appendix I.

** LET is Linear Energy Transfer = the density of fonization along an ion's path in MeV/(mg/cm²). The cosine law for beam angle is applied where valid to obtain "effective" LET.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix II.

**** Unless otherwise noted, the cross section (upsets/fluence per device) is given for 240-380 MeV Kr or Br at normal incidence, having an LET=36 to 40 MeV/(mg/cm²).

TABLE 2. (Cont'd)
Device

																												. antifuse																
	Remarks	484		1/32. Compare Jn; Aerospace data [5/90].	44/60 11- A- 408 00	11/32. Up 10 123 °C.	11/32. Up 10 123 °C.	Durour, 92 IEEE Workshop	Kinnison 4/92	Kimison 4/92	OS ICES WATER D. Law and	4/04 SEE Sum High Tems 440 cultic	Chamle at ESA Conf. 1400	92 IEEE Workshop Dufour 7/92 See Table 1	92 IEEE Workshop Dufour 7/92 See Table 1	IEEE '92. Proton LU also occurs.	April '91	Sferrino '91	Sferrino '91 Compare above.	Compare Table 1. 92 IEEE Workshop Dufour, 7/92	Sferrino '91	DC 9109	Sterrino '91	Date Code 9032	Sferrino '91	Sferrino '91	92 IEEE Workshop Dufour 7/92	DC 9109 [1] = 547 logic modules, 4 ports/module, config. antifuse	92 IEEE Workshop Dufour 7/92	92 IEEE Workshop Dufour 7/92	of ILLE Noivellap Dulour 1/92	700	6/65	Sferrino '91	9/92, saturated SEU=3E-5 cm ²	LIN: 1991; S ² : 1992	June 1991	92 IEEE Workshop Dufour 7/92	92 IEEE Workshop Dufour 7/92	3/92	12/92	12/92	1/91 NSC's FACT DC>8825 are designed Librarof	4/91
	Facility****	Na		9 1				CANIL	1 2	1 2 2 2 2 2 2 2 2 2 2 2 2 2 2 2 2 2 2 2	פאר	C4.259	Nd	GANIL	GANIL	Harwell	BNL	BNL	BK	GANIL	BNL	M	BNL	M	BNF	BN	GANIL	N.	GANIL	GANIL	Rin R	=	BNE	BNF	BNF	BNL	88-in	GANIL	GANIL	88-In	88-in	88-in	BN.	NA NA
Coss	Section (cm ²)**		l i	20.0	3				ı	1		8E-5		,		0.15[LET=12]		ı		4E-4	_	ı	ı	1E-3	1	1	1	1	ı		15-6	ì		ı	1	ı	8E-5			1	1	3E-4		
Effective	Threshold	8	3 5	¥ ¥	2 5	2 5	148	2 4	ū #	2 8	3 57	\$40	<55	>140	×140	?	12	×164	38 to 69	ĸ	<27	>54	>164	18	×164	× 454	×104	×27	09¢	Ş Ş	51 to 80	} } ;	>120	ឧ	×120	ଛ	6		>137	×100	×100		>120	<27
	Bits		ı	ı	ı	ı	1 1	60~70	ONAO!	1Kv9	1Kv9	9Kx8	8Kx8	8Kx8	32Kx8	64K	2Kx8	32Kx8	32Kx8	128Kx8	32Kx8	1Mx4	8Kx8	32Kx8	32Kx8	BKXB	RXXB	. 1	ı	1 1	ı		None	None	None	None	1	Quad	Dual	ı	t	1	1	1
	Mr.	DAT	\ <u>\</u>	CRV	ΑDI	Sds	S CS	I			MTA	CYP	MTA	MTA	MTA	NEC	₩ CN	¥ÇN	¥Ç.	S S S	토	¥CN	RAY	S X	SEQ	2	702	[L]VII		TRY ME	ADA		HAR	NSC	HAR	NSC	LTC	묾	SIL	SIL	HAR	LTC	NSC	PFS
	Technology		CMOS	CMOS/epi	CMOS	CMOS	CMOS	CMOS	CMOS	CMOS/epi	SCMOS/epi RT	CMOS	CMOS/ep1	SCMOS/epi RT	SCMOS/epi RT	CMOS		CMOS/epi	CMOS	CMOS/bulk	CMOS	CMOS/epi 0.8 µm epi	CMOS/epi? fuse-link	CMOS/FG	CMOS/epi	Cindolepir	Citocial	SCMOS(ep) DT	CMOS	CMOS	CMOS		CMOS/SOS	CMOS	CMOS/SOS	CMOS	CMOS	CMOS	CMOS	CMOS/epi 13 microns	CMOS	CMOS	FACT W. I/O	CIMOS
	Function	12-bit ADC	16-bit ADC	16-bit ADC	10-bit DAC	10-bit DAC	12-bit DAC	FIFO	<u>H</u>	<u> </u>	FIE	SRAM	SRAM	SHAM	SHAM	SRAM	SRAM	SRAM	SHAM	SHAM	SHAM	DHAM	SHOM	FEFFICIA	EFFECIM	PROM	EDGA	GA 35K	1553 Bus Cont.	Mut./Accum.	DC/DC Conv. module	(one IC)	Driver	Driver	Receiver	Receiver	Transcelver	Analog Switch	Analog Switch	Analog Switch	Analog MUX	Low Pass Filter	Logic	Logic
	Device	ADS112	CS5016	CS5016	AD7533	MP7533	SOR7541	7134RT	7202HT	7202RE	M67202	CYC185	HM65641	HM65664	HM65656	D4464D	MT5C1608	MT5C2568	M15C2568	MISCHOORCW	DESERVE	M14C1004C	H29/93	AZBCZ3B	280.530	MB7144F	1000A	MC5000	MA805	TMC2210	ATW28XX		26C31	26331	26532	26C32	LTC485CN8	DG271	DG300	DG601AK	IH6208	LTC1064	54ACTQ244	P54PCT245
Test	Org	3	SSS	⋖	7	->	MINE	5	=	GDD	MSS	œ	CNES	SI SI	S S	ESA	Z :	S :	<u> </u>	£ 3	LIN	CNES	SHE'S	Sec.	<u> </u>	MAS I	CNES	MAS	SE	MINS	⋖		-	즐 .	-	LINSSS	∢ :	SING	SE SE	⋖・	⋖ .	V	동 <u>:</u>	3

TECHNOLOGY OPERATIONS

The Aerospace Corporation functions as an "architect-engineer" for national security programs, specializing in advanced military space systems. The Corporation's Technology Operations supports the effective and timely development and operation of national security systems through scientific research and the application of advanced technology. Vital to the success of the Corporation is the technical staff's wide-ranging expertise and its ability to stay abreast of new technological developments and program support issues associated with rapidly evolving space systems. Contributing capabilities are provided by these individual Technology Centers:

Electronics Technology Center: Microelectronics, VLSI reliability, failure analysis, solid-state device physics, compound semiconductors, radiation effects, infrared and CCD detector devices, Micro-Electro-Mechanical Systems (MEMS), and data storage and display technologies; lasers and electro-optics, solid state laser design, micro-optics, optical communications, and fiber optic sensors; atomic frequency standards, applied laser spectroscopy, laser chemistry, atmospheric propagation and beam control, LIDAR/LADAR remote sensing; solar cell and array testing and evaluation, battery electrochemistry, battery testing and evaluation.

Mechanics and Materials Technology Center: Evaluation and characterization of new materials: metals, alloys, ceramics, polymers and composites; development and analysis of advanced materials processing and deposition techniques; nondestructive evaluation, component failure analysis and reliability; fracture mechanics and stress corrosion; analysis and evaluation of materials at cryogenic and elevated temperatures; launch vehicle fluid mechanics, heat transfer and flight dynamics; aerothermodynamics; chemical and electric propulsion; environmental chemistry; combustion processes; spacecraft structural mechanics, space environment effects on materials, hardening and vulnerability assessment; contamination, thermal and structural control; lubrication and surface phenomena; microengineering technology and microinstrument development.

Space and Environment Technology Center: Magnetospheric, auroral and cosmic ray physics, wave-particle interactions, magnetospheric plasma waves; atmospheric and ionospheric physics, density and composition of the upper atmosphere, remote sensing, hyperspectral imagery; solar physics, infrared astronomy, infrared signature analysis; effects of solar activity, magnetic storms and nuclear explosions on the earth's atmosphere, ionosphere and magnetosphere; effects of electromagnetic and particulate radiations on space systems; component testing, space instrumentation; environmental monitoring, trace detection; atmospheric chemical reactions, atmospheric optics, light scattering, state-specific chemical reactions and radiative signatures of missile plumes, and sensor out-of-field-of-view rejection.